

ABSTRACT

A method of tuning a resonant cavity of an FP (Fabre-Perot) interferometer in a DLD (diffractive light device) MEMS (microelectromechanical system) device, wherein the FP interferometer has a top plate and a bottom plate, and wherein the method comprises; using first and second electromechanical transducers to change distance between the top and bottom plates of the FP interferometer.